

Optical testing of polycrystalline silicon flexure-type optical actuators

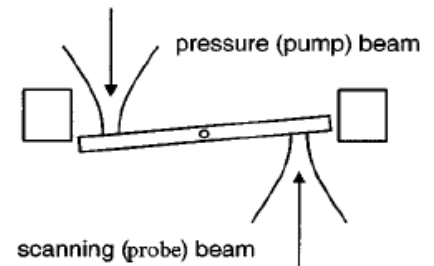
Justin R. Serrano and Leslie M. Phinney

Engineering Sciences Center
Sandia National Laboratories
Albuquerque, NM

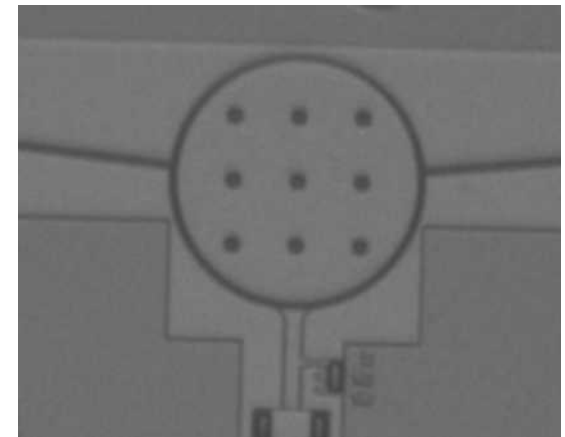
November 6th, 2006

Optical actuation in MEMS

- Requires no electrical connections → intrinsic isolation
- Compatible with harsh environments (radiation, high temperature, etc.)
- Enabling technology for all-optical MEMS devices
- Different actuation schemes include radiation pressure, use of photostrictive materials and **photothermal processes**



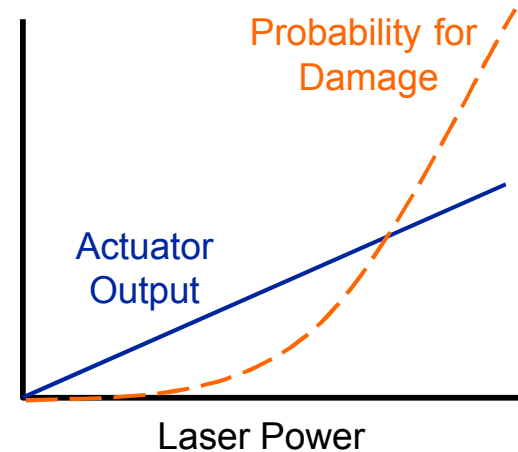
Graebner, Pau, and Gammel, *Appl. Phys. Lett.*, **81**, 3531 (2002)



Serrano, Phinney, and Brooks, *Proc. InterPACK'05*, IPACK2005-73322 (2005)

Photothermal Actuation

- Can take advantage of electro-thermal actuation techniques and designs
- Uses laser-induced heating of device to generate motion/force
- Performance limited by damage to device
- Improved performance obtained by:
 - maximizing actuator output
 - minimizing damage risk



Caveats:

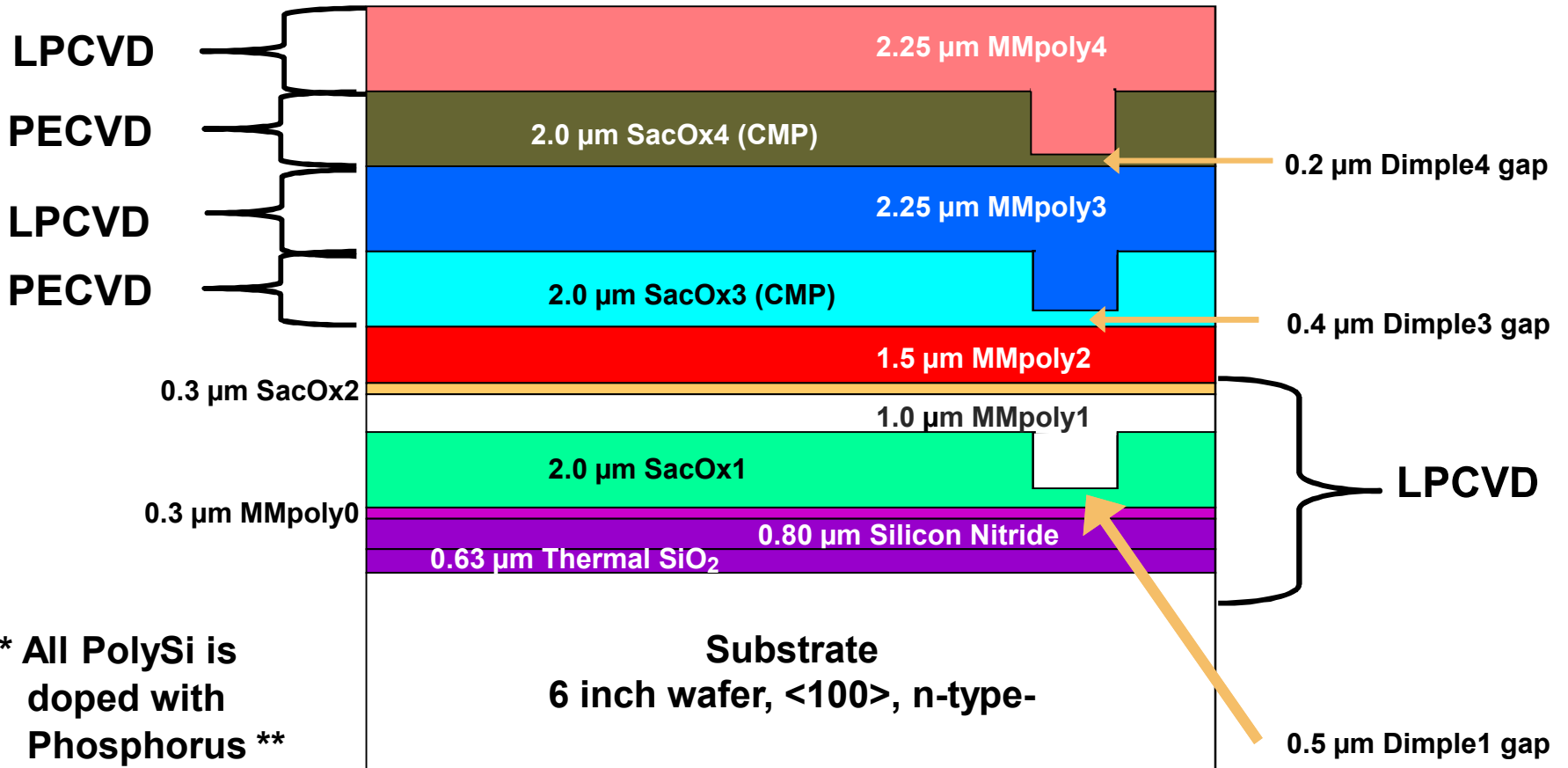
Damage risk and output are linked through applied power



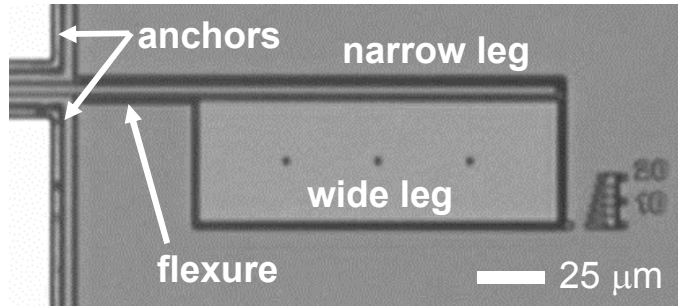
SUMMiT™ V

Sandia's Ultra-planar Multi-level MEMS Technology

SUMMiT™ Layer Descriptions



Flexure-type Optical Actuators



- **Actuator designs**

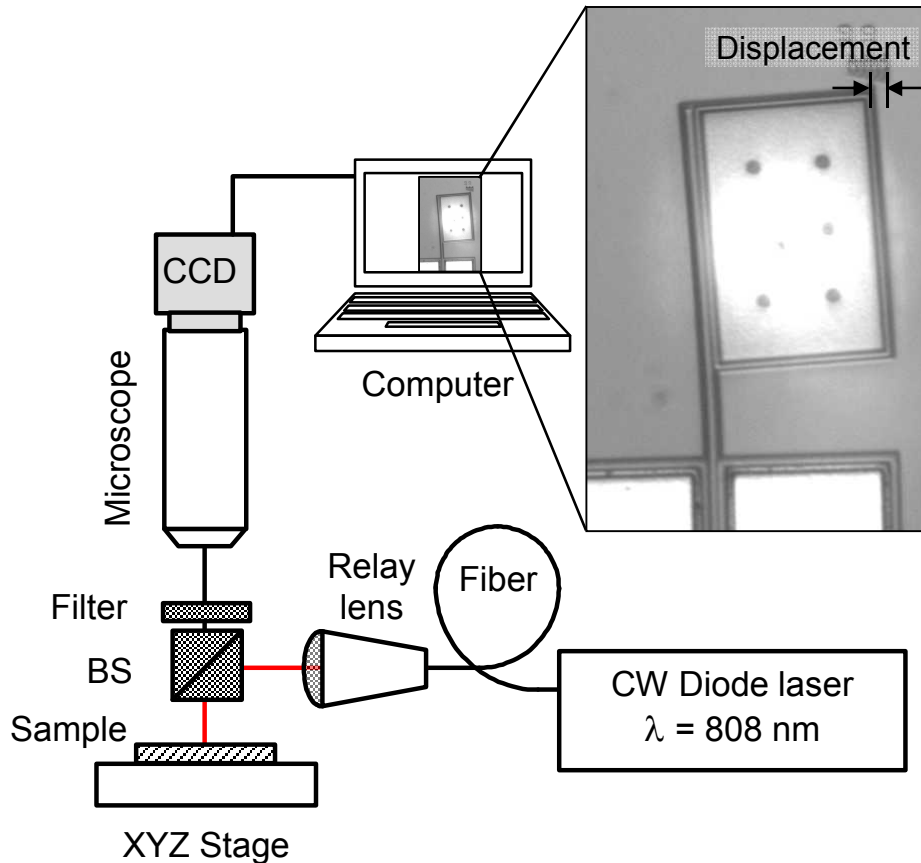
- Composition: P4-only or P3-P4 laminate
- Narrow leg: 2.5 x 200 μm
- Wide leg: 2.5 x (50/100) μm
- 50 μm flexure element
- 2.5/5.0 μm leg-leg distance

- **Dissimilar thermal expansion between hot and cold sides used to generate motion**
- **Compared to ET flexure actuators**

- Larger wide leg which serves as target for laser
- Wide leg is “hot” side of actuator
- Motion is in the opposite direction
- **Different failure mechanism**

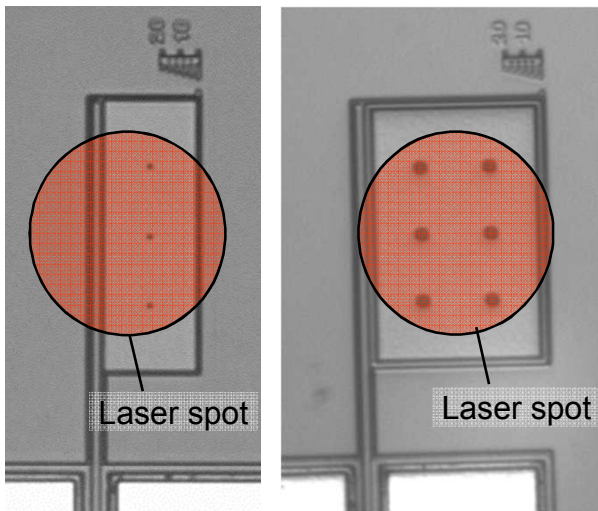


Experimental Details



- Actuators irradiated with 808 nm, fiber-coupled, CW diode laser; 100 μm diameter spot
- Laser power varied from 100-650 mW
- Images of actuators captured before, during and after irradiation

Experimental Details

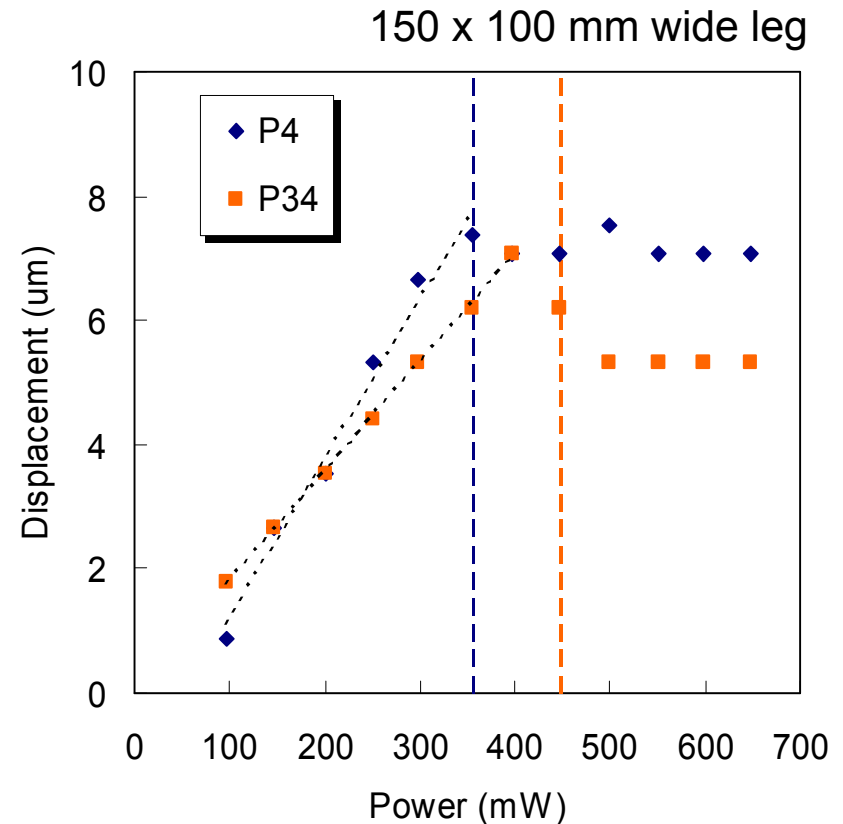


Laser spot centered on
100 μm wide leg; offset on
50 μm wide leg

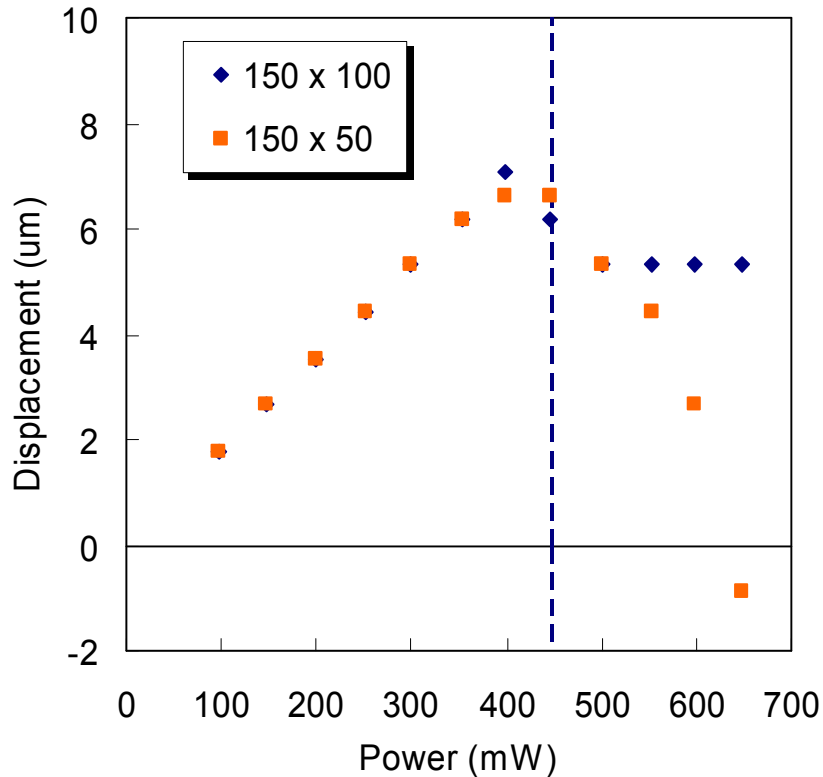
- Displacement measured at the top-right corner of device; determined with image analysis
- Displacement determined to ± 1 pixel (0.65 μm)
- Irradiation schemes:
 - **Power ramp:** laser power always incident on actuator, increased slowly; images captured at regular power intervals
 - **On/off irradiation:** images captured, laser power increased with each on/off cycle
 - **Prolonged exposure:** laser incident on actuator for extended period; images captured at regular time intervals

Target Composition

- **Displacement is linear with power up to initiation of surface damage**
- **Maximum displacement similar for both compositions**
- **After damage, displacement recedes slightly (P34) or remains constant**
- **P4-only actuators significantly more robust than previous studies; possibly due to interference**



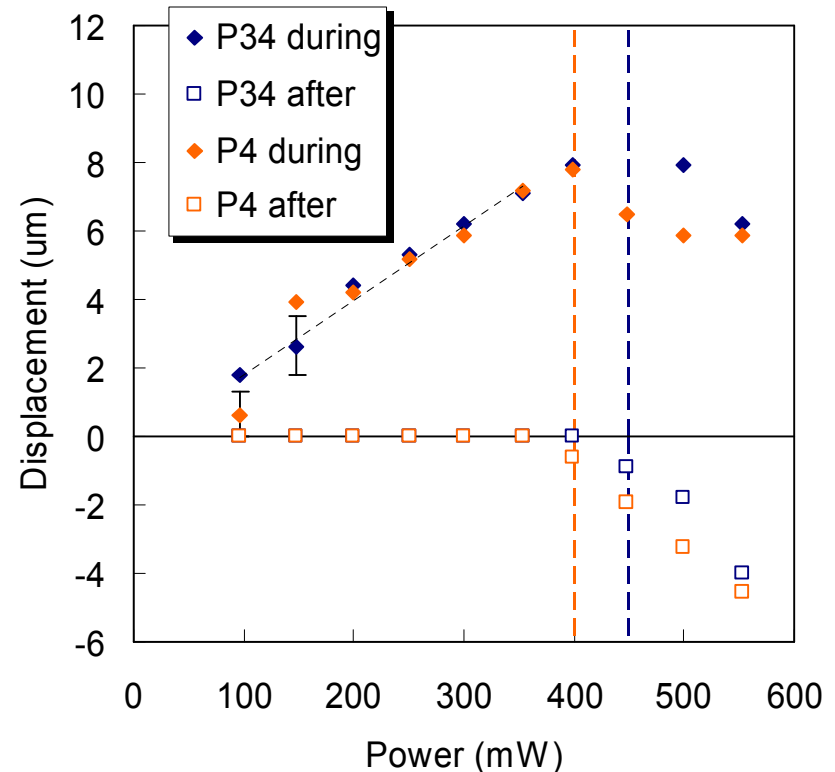
Displacement Recession



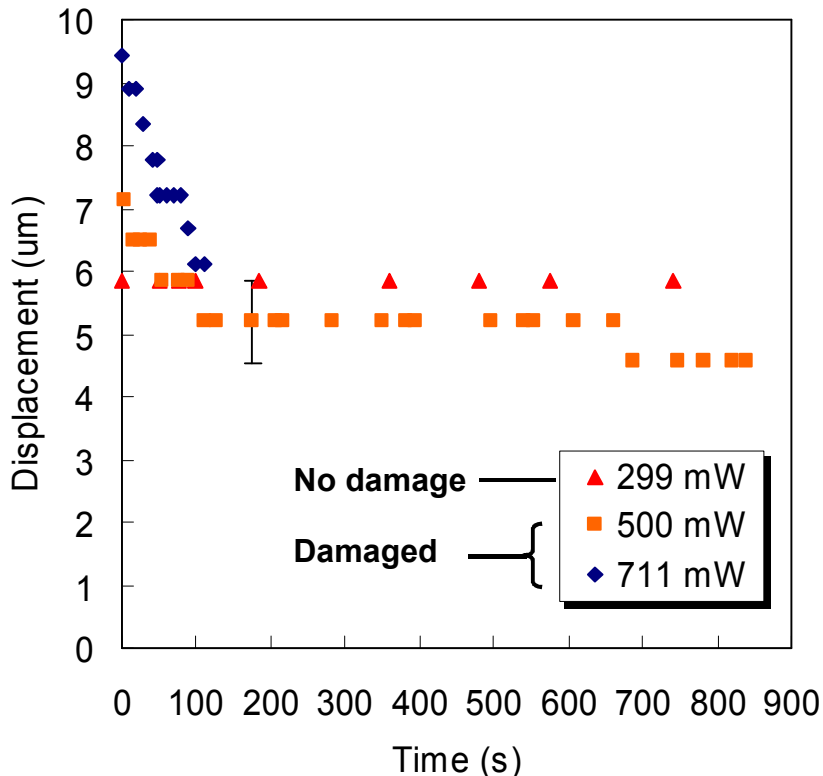
- **Narrower actuator shows significant recession in displacement after damage regardless of composition**
- **Displacement loss due to softening of the poly at elevated temperatures responsible for damage**
 - “Softening” compromises more of the actuator structure in the narrower device

On/Off Cycling

- **Cycling laser power on/off results in repeatable displacement in undamaged surface**
- **After damage, displacement recession is clearly evident after irradiation**
 - initial position recedes with increasing laser power
 - relaxation during the damage event results in thermal contraction upon cooling



Prolonged Exposure: More Recession



- At powers below damage, displacement holds constant
- If the surface is undamaged prior to irradiation, powers that produce damage:
 - Result in large displacement recession within first 200 s of irradiation;
 - Slight increase in surface damage size during first 60 s; minimal afterwards



Summary and Conclusions

- Polysilicon flexure type optical actuators were evaluated for performance and robustness to damage
- Because heating power is applied directly to members responsible for motion, displacement is linear with power for laser powers that do not produce damage ($P < 400 \text{ mW}$)
- Maximum displacement is 8-9 μm
- Increased incident power results in surface damage and recession in actuator displacement due to structural relaxation of the polysilicon layer
- Prolonged exposure to elevated laser powers further increases the recession in the displacement



Acknowledgements

- **Allen Gorby and Tom Grasser for experimental support**
- **Katie Francis and Rosemarie Renn for helping with the device design**
- **MDL Staff for the fabrication of the MEMS devices**